

# Jinxing Liang

## List of Publications by Year in descending order

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papers

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citations

1162889

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docs citations

23  
times ranked

296  
citing authors

#	ARTICLE	IF	CITATIONS
1	Fiber-Optic Temperature Sensor Based on Difference of Thermal Expansion Coefficient Between Fused Silica and Metallic Materials. IEEE Photonics Journal, 2012, 4, 155-162.	1.0	43
2	Improved bi-layer lift-off process for MEMS applications. Microelectronic Engineering, 2008, 85, 1000-1003.	1.1	25
3	Wet Etched High Aspect Ratio Microstructures on Quartz for MEMS Applications. IEEJ Transactions on Sensors and Micromachines, 2007, 127, 337-342.	0.0	22
4	NIR Spectrum Analysis of Natural Gas Based on Hollow-Core Photonic Bandgap Fiber. IEEE Sensors Journal, 2012, 12, 2362-2367.	2.4	22
5	Measurement of Low Gas Concentrations Using Photonic Bandgap Fiber Cell. IEEE Sensors Journal, 2010, 10, 1156-1161.	2.4	20
6	Fabrication of Photonic Bandgap Fiber Gas Cell Using Focused Ion Beam Cutting. Japanese Journal of Applied Physics, 2009, 48, 06FK05.	0.8	15
7	Flip Chip Bonding of a Quartz MEMS-Based Vibrating Beam Accelerometer. Sensors, 2015, 15, 22049-22059.	2.1	14
8	Doubled Optical Path Length for Photonic Bandgap Fiber Gas Cell Using Micromirror. Japanese Journal of Applied Physics, 2011, 50, 06GM01.	0.8	10
9	High Sensitive Tilt Sensor for Quartz Micromachining. IEEJ Transactions on Sensors and Micromachines, 2007, 127, 431-436.	0.0	9
10	An Experimental Study on Fabricating an Inverted Mesa-Type Quartz Crystal Resonator Using a Cheap Wet Etching Process. Sensors, 2013, 13, 12140-12148.	2.1	8
11	Development of Highly Integrated Quartz Micro-Electro-Mechanical System Tilt Sensor. Japanese Journal of Applied Physics, 2009, 48, 06FK10.	0.8	7
12	Fabrication of Two-Axis Quartz MEMS-Based Capacitive Tilt Sensor. IEEJ Transactions on Sensors and Micromachines, 2008, 128, 85-90.	0.0	7
13	Doubled Optical Path Length for Photonic Bandgap Fiber Gas Cell Using Micromirror. Japanese Journal of Applied Physics, 2011, 50, 06GM01.	0.8	5
14	Surface electrode configurations for quartz MEMS double-ended tuning fork resonator. Micro and Nano Letters, 2013, 8, 52-55.	0.6	5
15	Development of a Flow Injection Based High Frequency Dual Channel Quartz Crystal Microbalance. Sensors, 2017, 17, 1136.	2.1	5
16	Design and Fabrication of Quartz Micro-Electro-Mechanical System-Based Double-Ended Tuning Fork with Variable Sections. Japanese Journal of Applied Physics, 2011, 50, 06GM06.	0.8	5
17	Applied technique of focused ion beam milling based on microstructure of photonic bandgap fiber. International Journal of Advanced Manufacturing Technology, 2013, 68, 465-471.	1.5	4
18	Realization of quartz MEMS accelerometer based on flip chip process. , 2013, , .		4

#	ARTICLE	IF	CITATIONS
19	Characterization of a quartz MEMS tilt sensor with 0.001&#x00BA; precision. , 2009, , .		2
20	Design and Fabrication of Quartz Micro-Electro-Mechanical System-Based Double-Ended Tuning Fork with Variable Sections. Japanese Journal of Applied Physics, 2011, 50, 06GM06.	0.8	2
21	Study on Dual Channel Lateral Field Excitation Quartz Crystal Microbalance for Measuring Liquid Electrical Properties. Sensors, 2019, 19, 1253.	2.1	2
22	Damping Characteristics of Quartz Tilt Sensor with Nonparallel Comb Electrode. IEEJ Transactions on Sensors and Micromachines, 2013, 133, 37-41.	0.0	0
23	Design of the Self-test Structure of QVBA. , 2020, , .		0